Copper Interconnects Challenges

IC Interconnect

- A metal line which acts as a wire inside integrated circuits to connect various components
- Types: 1. Global Interconnect
 - 2. Local Interconnect.

Copper Interconnects

- Metal Deposition
 - o Physical vapor deposition (PVD)
 - Chemical vapor deposition (CVD)
 - Electroplating
- Advantages
 - o Low Resistivity (ρ).
 - o Reduced RC Delay.
 - o Low Electromigration.

Challenges

• Copper Diffusion

Problem: Copper diffusion into dielectric.

Solution: Create Barrier layer

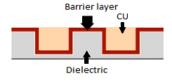
• Copper Oxidation

Problem: Oxidation reduces copper interconnects reliability.

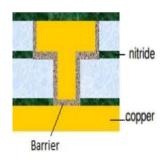
Solution: Create sealant layer.

• Electrochemical Migration:

- o Short circuit formation between interconnects under DC bias.
- Due to: Continuous moisture.
 - Two biased conductors.
 - Sealing defects.



Barrier Layer



Sealant Layer (nitride)